

## ABSTRACT

1           On embodiment relates to a loadlock having a first support structure therein to  
2           support one unprocessed substrate and a second support structure therein to support one  
3           processed substrate. The first support structure is located above the second support  
4           structure. The loadlock includes an elevator to control the vertical position of the support  
5           structures. The loadlock also includes a first aperture to permit insertion of an  
6           unprocessed substrate into the loadlock and removal of a processed substrate from the  
7           loadlock, as well as a second aperture to permit removal of an unprocessed substrate  
8           from the loadlock and insertion of a processed substrate into the loadlock. A cooling plate  
9           is also located in the loadlock. The cooling plate includes a surface adapted to support a  
10          processed substrate thereon. A heating device may be located in the loadlock above the  
11          first support structure.